

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s) : Volker BECKER et al.
Serial No. : To Be Assigned
Filed : Herewith
For : DEVICE AND METHOD FOR ETCHING A SUBSTRATE
BY USING AN INDUCTIVELY COUPLED PLASMA
Examiner : To Be Assigned
Art Unit : To Be Assigned

2A
9/12/02

Assistant Commissioner for Patents
Washington, D.C. 20231

**PRELIMINARY AMENDMENT AND
37 C.F.R. § 1.125 SUBSTITUTE SPECIFICATION STATEMENT**

S I R:

Kindly amend the above-captioned application before examination, as
set forth below.

IN THE SPECIFICATION AND ABSTRACT:

In accordance with 37 C.F.R. § 1.121(b)(3), a Substitute Specification
(including the Abstract, but without claims) accompanies this response. It is
respectfully requested that the Substitute Specification (including Abstract) be
entered to replace the Specification of record.

IN THE CLAIMS:

On the first page of the claims, first line, change "What is claimed is:"
to --WHAT IS CLAIMED IS:--.

Please cancel, without prejudice, claims 1 to 32 in the underlying PCT
application.

Please add the following new claims:

--33. (New) A device for etching a substrate, comprising: